

Message Text

CONFIDENTIAL

PAGE 01 STATE 220683

66

ORIGIN COME-00

INFO OCT-01 CIAE-00 DODE-00 EB-07 NRC-05 NSAE-00 USIA-06

TRSE-00 EUR-12 ERDA-05 ISO-00 (ISO) R

DRAFTED BY COMM/OEA:RGAREL:MRB

APPROVED BY EB/ITP/EWT:SGOODMAN

RPE

----- 127014

R 050246Z SEP 76

FM SECSTATE WASHDC

TO USMISSION OECD PARIS

C O N F I D E N T I A L STATE 220683

EXCON

EO. 11652:XGDS-1

TAGS: ESTC, COCOM, PL, US

SUBJECT: US VACUUM DEPOSITION SYSTEM TO POLAND - IL 1355
AND 1204

REF: (A) OECD PARIS 24107, (B) COCOM DOC (76) 1180

1. BROCHURE ASSOCIATED WITH THIS CASE STATES THAT "NEW ALLOY DEPOSITION TECHNIQUE PRODUCES SILICON-DOPED ALUMINUM METALLIZATION LAYERS THAT INHIBIT FURTHER SILICON DIFFUSION INTO ALUMINUM DURING HEAT TREATMENT. THIS TECHNIQUE PREVENTS SHORTS AT JUNCTIONS AND ALLOWS HIGHER SPEED THIN JUNCTION SEMICONDUCTOR DEVICES."

2. USE OF SPECIAL ROTATING FIXTURES COMBINED WITH THE USE OF ALUMINUM ALLOYED WITH SILICON METALLIZING MATERIAL RESULTS IN THIN, UNIFORM CIRCUIT METAL INTERCONNECTS WHICH DO NOT TEND TO ETCH OR DIFFUSE THROUGH THE SILICON OXIDE INTO THE ACTIVE SILICON REGIONS THEREBY CAUSING ELECTRICAL SHORTS. THIS PROPERTY OF PURE ALUMINUM TO
CONFIDENTIAL

CONFIDENTIAL

PAGE 02 STATE 220683

PENETRATE SILICON OXIDE DURING HEATING IS A WELL-KNOWN

DRAWBACK WHICH THE US MANUFACTURER PROPOSES TO COUNTER BY
USING A TWO PERCENT SILICON ALLOYED ALUMINUM MATERIAL.

THE VACUUM COATER IS USED ONLY TO DEPOSIT UNIFORMLY
THIN LAYERS OF THE ALUMINUM MATERIAL AND CANNOT PRODUCE
NEW TYPES OF SILICON JUNCTIONS.

3. IT IS HOPED THIS ADDITIONAL INFORMATION WILL
ENABLE FRENCH TO APPROVE CASE. ROBINSON

CONFIDENTIAL

NNN

Message Attributes

Automatic Decaptioning: X
Capture Date: 01 JAN 1994
Channel Indicators: n/a
Current Classification: UNCLASSIFIED
Concepts: STRATEGIC TRADE CONTROLS, EXCEPTIONS LIST, ELECTRIC EQUIPMENT
Control Number: n/a
Copy: SINGLE
Draft Date: 05 SEP 1976
Decaption Date: 01 JAN 1960
Decaption Note:
Disposition Action: RELEASED
Disposition Approved on Date:
Disposition Authority: GolinoFR
Disposition Case Number: n/a
Disposition Comment: 25 YEAR REVIEW
Disposition Date: 28 MAY 2004
Disposition Event:
Disposition History: n/a
Disposition Reason:
Disposition Remarks:
Document Number: 1976STATE220683
Document Source: CORE
Document Unique ID: 00
Drafter: RGAREL:MRB
Enclosure: n/a
Executive Order: X1
Errors: N/A
Film Number: D760337-0085
From: STATE
Handling Restrictions: n/a
Image Path:
ISecure: 1
Legacy Key: link1976/newtext/t19760988/aaaacxqj.tel
Line Count: 70
Locator: TEXT ON-LINE, ON MICROFILM
Office: ORIGIN COME
Original Classification: CONFIDENTIAL
Original Handling Restrictions: n/a
Original Previous Classification: n/a
Original Previous Handling Restrictions: n/a
Page Count: 2
Previous Channel Indicators: n/a
Previous Classification: CONFIDENTIAL
Previous Handling Restrictions: n/a
Reference: 76 OECD PARIS 24107
Review Action: RELEASED, APPROVED
Review Authority: GolinoFR
Review Comment: n/a
Review Content Flags:
Review Date: 21 APR 2004
Review Event:
Review Exemptions: n/a
Review History: RELEASED <21 APR 2004 by CollinP0>; APPROVED <21 APR 2004 by GolinoFR>
Review Markings:

Margaret P. Grafeld
Declassified/Released
US Department of State
EO Systematic Review
04 MAY 2006

Review Media Identifier:
Review Referrals: n/a
Review Release Date: n/a
Review Release Event: n/a
Review Transfer Date:
Review Withdrawn Fields: n/a
Secure: OPEN
Status: NATIVE
Subject: US VACUUM DEPOSITION SYSTEM TO POLAND - IL 1355 AND 1204
TAGS: ESTC, PL, US, COCOM
To: OECD PARIS
Type: TE
Markings: Margaret P. Grafeld Declassified/Released US Department of State EO Systematic Review 04 MAY 2006